

Technische Universität Graz

Institute of Solid State Physics

Intrinsic semiconductors

Silicon band structure

Near the bottom of the conduction band, the band structure looks like a parabola.

Effective mass

This effective mass is used to describe the response of electrons to external forces in the particle picture.

$$
\vec{F} = -e\vec{E} = m^*\vec{a}
$$

valence band, holes

When all states in a band are occupied, the band does not contribute to the current. There are as many left-moving electrons as right-moving electrons. \rightarrow

$$
I \propto \sum_{\text{occupied } \vec{k}} \left(-e \vec{\mathbf{v}}_{\vec{k}} \right)
$$

$$
I \propto \sum_{\text{all } \vec{k}} \left(-e \vec{\mathbf{v}}_{\vec{k}} \right) - \sum_{\text{empty } \vec{k}} \left(-e \vec{\mathbf{v}}_{\vec{k}} \right)
$$

$$
I \propto \sum_{\text{empty } \vec{k}} e \vec{v}_{\vec{k}}
$$

valence band, holes

In the valence band, the effective mass is negative.

Holes

Charge carriers in the valence band can be considered to be positively charged holes. The number of holes in the valence band is the number of missing electrons.

 m^* _h = effective mass of holes

$$
m_h^* = -\frac{\hbar^2}{\frac{d^2E(\vec{k})}{dk_x^2}}
$$

$$
\vec{F} = e\vec{E} = m_h^* \vec{a}
$$

Silicon density of states

Boltzmann approximation

Density of electrons in the conduction band

of electrons in the conduction band

\n
$$
n = \int_{E_c}^{\infty} D(E)f(E)dE \approx D_c \int_{E_c}^{\infty} \exp\left(\frac{E_F - E}{k_B T}\right) \sqrt{E - E_c} dE
$$
\n
$$
x = E - E_c \qquad \int_{0}^{\infty} \sqrt{x} \exp\left(\frac{-x}{k_B T}\right) dx = \frac{2}{\sqrt{\pi}} \left(k_B T\right)^{3/2}
$$
\n
$$
n = \frac{2D_c}{\sqrt{\pi}} (k_B T)^{3/2} \exp\left(\frac{E_F - E_c}{k_B T}\right) = \boxed{N_c(T) \exp\left(\frac{E_F - E_c}{k_B T}\right)}
$$

$$
x = E - E_c
$$

\n
$$
\int_{0}^{\infty} \sqrt{x} \exp\left(\frac{-x}{k_B T}\right) dx = \frac{2}{\sqrt{\pi}} (k_B T)^{3/2}
$$

\n
$$
n = \frac{2D_c}{\sqrt{\pi}} (k_B T)^{3/2} \exp\left(\frac{E_F - E_c}{k_B T}\right) = N_c(T) \exp\left(\frac{E_F - E_c}{k_B T}\right)
$$

\n
$$
N_c = \frac{2D_c}{\sqrt{\pi}} (k_B T)^{3/2} = 2 \left(\frac{m^* k_B T}{2\pi \hbar^2}\right)^{3/2} = \text{effective density of states of the conduction band}
$$

$$
N_c = \frac{2D_c}{\sqrt{\pi}} (k_B T)^{3/2} = 2 \left(\frac{m^* k_B T}{2\pi \hbar^2} \right)^{3/2} = \text{effective density of states}
$$
of the conduction band

Density of holes in the valence band

$$
D(E) = D_v \sqrt{E_v - E}
$$

$$
1 - f(E) = 1 - \frac{1}{1 + \exp\left(\frac{E - E_F}{k_B T}\right)} \approx \exp\left(\frac{E - E_F}{k_B T}\right)
$$

Boltzmann approximation

Density of holes in the valence band

$$
p = \int_{-\infty}^{E_v} D(E) (1 - f(E)) dE \approx D_v \int_{-\infty}^{E_v} \exp\left(\frac{E - E_F}{k_B T}\right) \sqrt{E_v - E} dE
$$

\n
$$
p = \frac{2D_v}{\sqrt{\pi}} (k_B T)^{3/2} \exp\left(\frac{E_v - E_F}{k_B T}\right) = N_v (T) \exp\left(\frac{E_v - E_F}{k_B T}\right)
$$

$$
p = \frac{2D_v}{\sqrt{\pi}} (k_B T)^{3/2} \exp\left(\frac{E_v - E_F}{k_B T}\right) = \left| N_v(T) \exp\left(\frac{E_v - E_F}{k_B T}\right) \right|
$$

$$
N_v = 2 \left(\frac{m_h^* k_B T}{2 \pi \hbar^2} \right)^{3/2} = \text{Effective density of states in}
$$

Boltzmann approximation

Near the top of the valence band and the bottom of the conduction band the density of states of a semiconductor can be approximated as,

$$
D(E)=\left\{\begin{matrix} D_v\sqrt{E_v-E},&\text{for }E
$$

Where D_v and D_c are constants that describe the form of the density of states near the band edges. Often in the literature, these constants are given in terms of the 'densit states effective masses' m_h^* and m_e^* or the 'effective density of states at 300 K' $N_v(300)$ and $N_c(300)$. The relations to D_v and D_c are,

$$
D_v = \frac{(2m_h^*)^{3/2}}{2\pi^2\hbar^3} = \frac{\sqrt{\pi}N_v(300)}{2(k_BT)^{3/2}}, \qquad D_c = \frac{(2m_e^*)^{3/2}}{2\pi^2\hbar^3} = \frac{\sqrt{\pi}N_c(300)}{2(k_B300)^{3/2}}
$$

Data for different semiconducting materials can be found in the NSM Archive.

The plot below shows the density of states of various semiconductors in this approximation. The Fermi function is plotted as well. At low energies the value of the Fermi function is 1 and those states are occupied. At high energies the Fermi function goes to zero and those states are unoccupied. In the limit of low temperture, the Fermi eno the middle of the band gap, $E_F = E_q/2$. As the temperature increases, the Fermi energy moves towards the band with the lower density of states.

Density of electrons in the conduction band

Silicon valence bands

$$
\begin{array}{l} E_{v,lh}=-\displaystyle\frac{\hbar^2}{2m_e}\Big(4.1k^2-\sqrt{1.21k^4+4.1(k_x^2k_y^2+k_x^2k_z^2+k_y^2k_z^2)}\Big)\,,\\ \\[2mm] E_{v,hh}=-\displaystyle\frac{\hbar^2}{2m_e}\Big(4.1k^2+\sqrt{1.21k^4+4.1(k_x^2k_y^2+k_x^2k_z^2+k_y^2k_z^2)}\Big)\,,\\ \\[2mm] E_{v,so}=-E_{so}-\displaystyle\frac{\hbar^2k^2}{2m_{so}}.\end{array}
$$

Density of holes in the valence band

$$
p = 2 \left(\frac{m_h^* k_B T}{2 \pi \hbar^2} \right)^{3/2} \exp \left(\frac{E_v - E_F}{k_B T} \right)
$$

New Semiconductor Materials. Biology systems.
Characteristics and Properties

http://www.matprop.ru/semicond

Exam March 2007 Problem 1

The band structure of a semiconductor is shown below. The zero of energy is chosen to be the top of the valence band.

(a) Is this a direct or an indirect semiconductor? Why?

(c) What are light holes and heavy holes? Explain how you can determine the effective mass of the holes from this diagram.

⁽b) What is the band gap?

Law of mass action

$$
np = N_c \exp\left(\frac{E_F - E_c}{k_B T}\right) N_v \exp\left(\frac{E_v - E_F}{k_B T}\right) E_c
$$

$$
np = N_c(T) N_v(T) \exp\left(\frac{-E_g}{k_B T}\right) E_v
$$

For intrinsic semiconductors (no impurities)

$$
n = p = n_i = \sqrt{N_c(T)N_v(T)} \exp\left(\frac{-E_g}{2k_B T}\right)
$$

intrinsic carrier density

Intrinsic carrier concentration

Good for thermometer, bad for designing circuits.

Fermi energy of an intrinsic semiconductor

$$
n = p = N_c \exp\left(\frac{E_F - E_c}{k_B T}\right) = N_v \exp\left(\frac{E_v - E_F}{k_B T}\right)
$$

$$
\frac{N_v}{N_c} = \exp\left(\frac{E_F - E_c - E_v + E_F}{k_B T}\right)
$$

$$
\frac{2E_F}{k_B T} = \frac{E_c + E_v}{k_B T} + \ln\left(\frac{N_v}{N_c}\right)
$$

$$
E_F = \frac{E_c + E_v}{2} + \frac{k_B T}{2} \ln\left(\frac{N_v}{N_c}\right)
$$

Temperature dependence of E_F

Intrinsic semiconductors

http://lamp.tu-graz.ac.at/~hadley/ss1/semiconductors/intrinsic_so.php

Technische Universität Graz

Extrinsic semiconductors

The introduction of impurity atoms that can add electrons or holes is called doping.

n-type : donor atoms contribute electrons to the conduction band. Examples: P, As in Si.

p-type : acceptor atoms contribute holes to the valence band. Examples: B, Ga, Al in Si.

Technische Universität Graz

n and p

The electron density and hole density are:

$$
n = N_c \exp\left(\frac{E_F - E_c}{k_B T}\right) \qquad p = N_v \exp\left(\frac{E_v - E_F}{k_B T}\right)
$$

The law of mass action:

$$
np = n_i^2 = N_v N_c \exp\left(-\frac{E_g}{k_B T}\right)
$$

Ionization of dopants

Easier to ionize a P atom in Si than a free P atom

$$
E_n = -\frac{me^4}{8\varepsilon_0^2 h^2 n^2}
$$

Ionization energy is smaller by a factor:

$$
\frac{m^*}{m} \left(\frac{\varepsilon_0}{\varepsilon_r \varepsilon_0}\right)^2
$$

Ionization energy \sim 25 meV

Crystal growth

Czochralski Process

Melting of polysilicon, doping

Introduction Beginning of of the seed the crystal crystal growth

Crystal pulling

Formed crystal with a residue of melted silicon

add dopants to the melt

images from wikipedia

Crystal growth
Float zone Process
Neutron transmutation
 $30Si + n \rightarrow 31Si + \gamma$
 $31Si \rightarrow 31P + \beta$ Crystal growth

Float zone Process

Neutron transmutation

 ${}^{31}\text{Si} \rightarrow {}^{31}\text{P} + \beta$

image from wikipedia

Gas phase diffusion

 AsH_3 (Arsine) or PH₃ (phosphine) for n-doping B_2H_6 (diborane) for p-doping.

http://www.microfab.de/foundry/services/diffusion/index.html

Chemical vapor deposition

Epitaxial silicon CVD SiH_4 (silane) or SiH_2Cl_2 (dichlorosilane) PH₃ (phosphine) for n-doping or B_2H_6 (diborane) for p-doping.

image from wikipedia

Ion implantation

Implant at 7º to avoid channeling

SRIM The Stopping and Range of Ions in Matter

James F. Ziegler, Jochen P. Biersack, Matthias D. Ziegler

- Ch 1 Historical Review
- Ch 2 Nuclear Stopping of Ions
- Ch 3 Electronic Stopping of Ions
- Ch 4 Stopping of Energetic Light Ions
- Ch 5 Stopping of Ions in Compounds
- Ch 6 Ion Straggling
- Ch 7 TRIM : Scientific Background
- Ch 8 TRIM : Setup and Input
- Ch 9 TRIM : Output Files
- Ch 10 Stopping and Range Tables
- Ch 11 SRIM Tutorials

SRIM The Stopping and Range of Ions in Matter

J. F. Ziegler J. P. Biersack M. D. Ziegler

http://www.synopsys.com

Donors

Five valence electrons: P, As

States are added in the band gap just below the conduction band

n-type: $n \sim N_D$ Many more electrons in the conduction band than holes in the valence band.

majority carriers: electrons; minority carriers: holes

Acceptors

Three valence electrons: B, Al, Ga

States are added in the band gap just above the valence band

p-type: $p \sim N_A$ Many more holes in the valence band than electrons in the conduction band.

majority carriers: holes; minority carriers: electrons

Donor and Acceptor Energies

Energy below the conduction band Energy above the valence band

Source: Semiconductor Devices Physics and Technology, S.M. Sze, 1985

Direct Observation of Friedel Oscillations around Incorporated Si_{Ga} Dopants in GaAs by Low-Temperature Scanning Tunneling Microscopy

M. C. M. M. van der Wielen, A. J. A. van Roij, and H. van Kempen

Research Institute for Materials, University of Nijmegen, Toernooiveld 1, 6525 ED Nijmegen, The Netherlands (Received 25 July 1995)

Temperature dependence

